

Notice of References Cited

Application/Control No.

10/587,254

Applicant(s)/Patent Under
Reexamination
OMURA, YASUHIRO

Examiner

COLIN KREUTZER

Art Unit

2882

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	U	Levinson, Harry J. Principles of Lithography Bellingham, WA: SPIE Press, 2001. Pages 205-206			
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*A copy of this reference is not being furnished with this Office action. (See MPEP § 707.05(a).)
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